		Reg. No. :										
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		Question Paper C	Cod	e: 9	5T2	5						
		Ph.D. COURSE WORK EXAM	MIN	ATI	DN, 1	NOV	201	9				
		Elective	e									
		Power Electronics	and	Driv	ves							
19PPE525– MICRO ELECTRO MECHANICAL SYSTEMS												
		(Regulation	2019	<b>)</b> )								
Du	ration	a: Three hours					Max	kimu	m: 1	00 N	larks	5
		Answer ALL Q	uest	ions								
		PART - A (5 x 20 =	= 100	) Ma	rks)							
1.	(a)		catic	n pro	ocess	5.			CO	1 <b>-</b> U		(20)
	(b)	Or Explain in detail about the steps involved	d in	silie	on h	ased	MEI	AV.	CO	1_ TT		(20)
	(0)	process	u 111	SIIIC		ascu	101121	VIS	CO	1- 0		(20)
2.	(a)	Briefly explain about the capacitance, equ in effect of parallel plate actuators	ilibr	ium	posit	ion a	ind p	oull	CO	2- U		(20)
		Or										
	(b)	Explain in detail about the flow sensor.							CO	2- U		(20)
3.	(a)	Briefly explain about thermal actuator	• <b>c</b> 0	nd ·	fund	men	talc	of	$CO^{\prime}$	3_ <b>I</b> ⊺		(20)
5.	( <i>a</i> )	thermal transfer	.s a	iiu .	lunua	inch	lais	01	CO.	5-0		(20)
		Or										
	(b)	Discuss in detail about thermal accelero mass and without any moving mass.	mete	ers b	ased	on	mov	ing	CO	3- U		(20)
		mass and writiout any moving mass.										
4.	(a)	Describe the common piezoelectric	m	ateri	als	and	th	neir	CO	4 <b>-</b> U		(20)
		representative properties.										
	(b)	Or Illustrate the fabrication of piezoelectri	C Se	ensoi	s us	sing	surf	ace	CO	4- U		(20)
	(-)	micromachining process and bulk microma				-				C		( -)

5.	(a)	Design a device with piezo resistive material to measure heart wall accelerations and also explain its fabrication process.	CO5- U	(20)
		Or		
	(b)	Analyze blood pressure sensor with design considerations	CO5- U	(20)